



**PATENT**

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5/14/02

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application No.: 09/361,980  
Filing Date: July 28, 1999  
Applicant: Yasuaki Tsuzuki et al.

Group Art Unit: 1765

Examiner: L. Umez Eronini

Title: Method of Etching Metallic Thin Film on Thin Film Resistor

Attorney Docket: 4041J-000439

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Commissioner of Patents and Trademarks  
Washington, D.C. 20231

**AMENDMENT AND PETITION FOR EXTENSION OF TIME**

Sir:

In response to the Office Action mailed December 19, 2001, Paper No. 12, please amend the application as follows and consider the remarks set forth below.

Applicant hereby petitions under the provisions of 37 C.F.R. § 1.136(a) for a one-month extension of time in which to respond to the outstanding Office Action. Applicant has included a Fee Transmittal with this response for such extension of time.

**IN THE CLAIMS**

Please cancel Claims 5, 6, 12-25 and 28-32; and amend Claims 7-11, 26 and 27. Applicant includes herewith an Attachment for Claim Amendments showing a